

U.S.S.N. 09/976,082

of ENDURA® 5500. In some of the sputter chambers, the wafer holder is structured as a pedestal which includes an internal resistive heater.

In the Claims

Claim 15 has been cancelled without prejudice.

Claim 3 has been amended as follows:

3. (Amended) A wafer lifter for self-centering a wafer on a pedestal according to claim 1, wherein a base of said slanted shoulder portion of the support finger defines a diameter of a circular area surrounded by the platforms of the at least four support fingers which is not larger than a diameter of said wafer when measured at 23°C.

REMARKS

Thorough examination and careful review of the application by the Examiner is noted and appreciated.

Claims 1, 3-5 and 7-15 are pending in the application.